

# Vapor Phase Growth of High Quality Monolayer MoS<sub>2</sub> at Low Temperature

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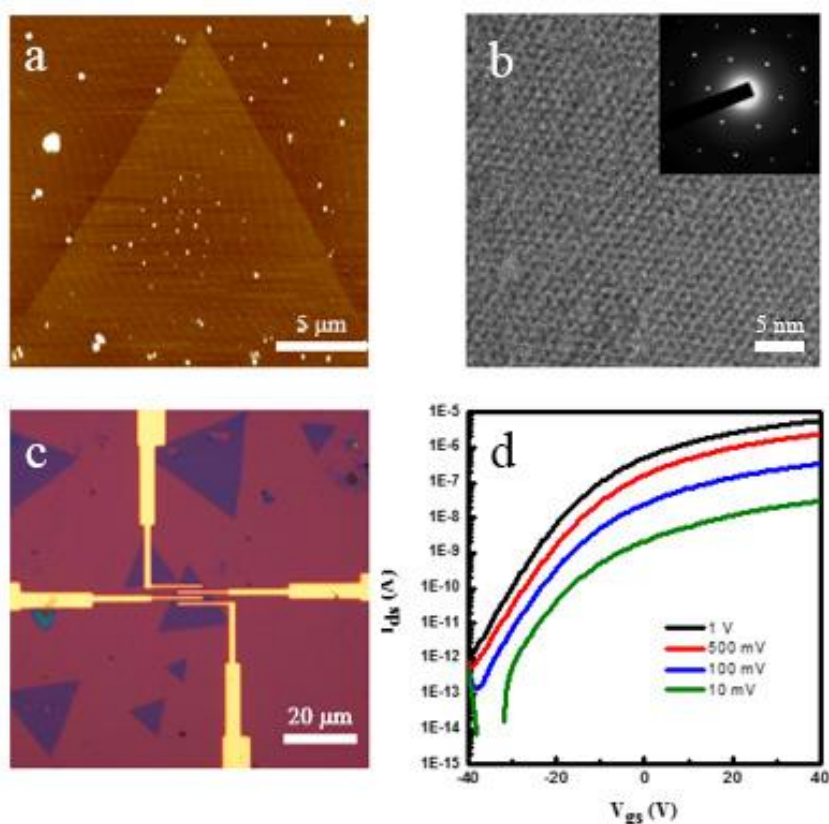
## Abstract

Two-dimensional (2D) MoS<sub>2</sub> atomic layer has received extensive attentions due to its outstanding electrical properties and catalysis activity. However, it remains challenging for synthesizing high quality MoS<sub>2</sub> monolayers at temperature lower than 600 °C for its applications in nanoelectronic and optoelectronic devices on various substrates. Here, we present a novel strategy for synthesizing monolayered MoS<sub>2</sub> in vapor phase at a growth temperature of 400 °C by optimizing the growth parameters. The obtained MoS<sub>2</sub> are mostly monolayered triangular flakes showing high crystallinity with side lengths of ~20 μm. The on/off current ratios and mobility of the field effect transistors (FETs) fabricated on the as made MoS<sub>2</sub> were in the ranges of 10<sup>5</sup>–10<sup>6</sup> and 1.0–2.0 cm<sup>2</sup> V<sup>-1</sup> s<sup>-1</sup>, respectively, comparable with those of backgated FETs made with mechanically exfoliated and chemical vapor deposited MoS<sub>2</sub> flakes.<sup>[1,2]</sup> This simple method provides a facile and convenient approach for preparing high quality monolayer MoS<sub>2</sub> and opens up a new way for synthesizing other high quality two-dimensional transition metal dichalcogenides.

## References

- [1] Wang Q H, S. Strano M, et al. Nature nanotechnology, **11** (2012) 699-712.  
[2] Wang X S, Jiao L Y, et al. Journal of the American Chemical Society, **14** (2013) 5304-5307.

## Figures



(a) Atomic Force microscope (AFM) image of the as-made MoS<sub>2</sub> flake. (b) High-resolution Transmission electron microscope (TEM) image of MoS<sub>2</sub> and selected area electron diffraction (SAED) patterns taken on a typical area of MoS<sub>2</sub> flakes (inset). (c) Optical image of a back-gated FET with a MoS<sub>2</sub> flake as channel. (d) I<sub>dk</sub>-V<sub>gs</sub> curves for the device in (c).